

#### ABSTRACT OF THE DISCLOSURE

A MEMS-type resonator and a method for manufacturing thereof are provided, in which an adsorption of a beam into a substrate in a wet process when manufacturing a MEMS is prevented and other oscillation modes, which are unnecessary, than a required oscillation mode are not mixed at the time of operation. Further, a communication apparatus including a filter that has the MEMS-type resonator is provided.

The MEMS-type resonator includes a substrate in which a lower electrode is formed and a beam formed on the substrate, in which at least one support column is provided between the substrate and the beam. As a filter, the communication apparatus includes a filter of the above MEMS-type resonator.